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Design, Fabrication, And Analysis Of MEMS Three-Direction ...Design, Fabrication, And Analysis Of MEMS Three-Direction Capacitive
Accelerometer Kevin Petscha And Dr. Tolga Kayaa A Central Michigan University,
Mount Pleasant, MI 48859 Email: {petsc1k, Kaya2t}@cmich.edu Abstract In This

Project We Present The Design And Fabrication Of A MEMS Three-direction Capacitive Accelerometer. Feb 1th, 2024
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DESIGN AND FABRICATION OF A MEMS CHEMICAPACITIVE SENSOR ...A Conceptual Design Of The Sensor Was Proposed At The Inception Of This Project By Professor Jeff Jessing. From This, A Detailed Design And Process Integration Was Developed. From The Process Integration Flow, A Photolithography Mask Set Was Designed And Purchased. All Fabrication Was Done In-house At Boise State University. Fabrication Tools And Mar 1th, 2024
Design And Testing Of A MEMS Acoustic Emission Sensor System
Keywords: Acoustic Emissions, MEMS, Damping, Transducer Sensitivity, In-plane Sensing
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